| L Number | Hits | Search Text | DB | Time stamp |
|---|---|---|---|---|
| 7 | 14031 | (photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:05 |
| 8 | 2507 | ((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:41 |
| 9 | 948 | (((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:41 |
| 10 | 503 | ((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:41 |
| 11 | 77 | (((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:42 |
| 13 | 48 | ((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4 | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:44 |

| 14 | 35 | (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4) and pattern$1 | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:44 |
| 15 | 18 | (((((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4) and pattern$1) and (mask$4 with pattern$1) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:48 |
| 16 | 17 | (((((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4) and pattern$1) not (((((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4) and pattern$1) and (mask$4 with pattern$1)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 08:50 |

| 17 | 29 | (((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) not ((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) and align$4) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:03 |
| 19 | 426 | ((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) not ((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:03 |

| 20 | 115 | (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) not ((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4)  same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.)) and ((photoresist or photosensitive) adj layer$1) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:11 |

| 21 | 311 | (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) not (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.)) not (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) not (((((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and 347/$.ccls.)) and ((photoresist or photosensitive) adj layer$1)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:15 |

| 22 | 445 | ((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) not (((((photoresist or photosensitive) and (mask$4 or print$4 or record$4) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) ) and ((circul$6 or rotat$5) same (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) and ((jet$4 or eject$4 or discharg$4) same (mask$4 or print$4 or record$4) same (photosensitive or photoresist))) and ((circul$6 or rotat$5) with (stage$1 or table$1 or subtrate$1 or wafer$1 or objet$1))) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/10/29 09:16 |